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ABSTRACTIMAGING METHOD FOR . MANUFACTURE OF MICRODEVICES

An imaging method for imaging a fine pattern having linear features extending along orthogonal first and second directions, is disclosed which method is characterized by: providing a light source having decreased intensity portions at a center thereof and on first and second axes defined to intersect with each other at the center and defined along the first and second directions, respectively; and illuminating the pattern with light from the light source.

FIG. 6A & 6B